

ABSTRACT OF THE DISCLOSURE

A defect inspection system according to the present invention comprises image acquiring section for acquiring a two-dimensional image of a subject which is a processing target in a manufacturing process, defect extracting section for extracting a defect by a defect extraction algorithm using a predetermined parameter for an image acquired by the image acquiring section, displaying section for displaying an image of a defect of the subject extracted by the defect extracting section, parameter adjusting section for adjusting the parameter in accordance with a defect extraction degree for the subject, and quality judging section for judging the quality of the subject based on a defect information extracted by the defect extracting section.

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